

Form PTO-1449  <b>U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE</b>				ATTY. DOCKET NO. MI22-1913		SERIAL NO. 10/050,334	
				APPLICANT: Vishnu K. Agarwal et al.			
				FILING DATE January 15, 2002		GROUP 2813	
<b>U.S. PATENT DOCUMENTS</b>							
Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
TN	AA	6,359,295 B2	03/2002	Yang et al. Lee et al.	—	—	
	AB	6,403,156	06/2002	Jang	—	—	
	AC	6,598,602 B2	07/2003	Lizuka et al.	—	—	
	AD	6,627,462 B1	09/2003	Yang et al.	—	—	
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TN	AF	6,746,930	06/2004	Yang	—	—	
	AG				—	—	
TN	AH	2002/0142488	10/2002	Hong, Suk-Kyoung	—	—	
TN	AI	2002/0109198 A1	08/2002	Yang et al.	—	—	
<b>FOREIGN PATENT DOCUMENTS</b>							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
TN	AJ	KR 2002046433	05/2003	Lee, J.W.	—	—	
TN	AK	EP 1 508 906 A2	02/2005	Lee et al.	—	—	
	AL				—	—	
<b>OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)</b>							
TN	AM	Ritala et al.; Perfectly Conformal TiN and Al203 Films Deposited by Atomic Layer Deposition; Chemical					
		Vapor Deposition, v. 5, No. 1, 1999, pp. 7-9.					
	AM						
	AO						
EXAMINER <i>T. Neuner</i>		DATE CONSIDERED <i>11/19/05</i>					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							